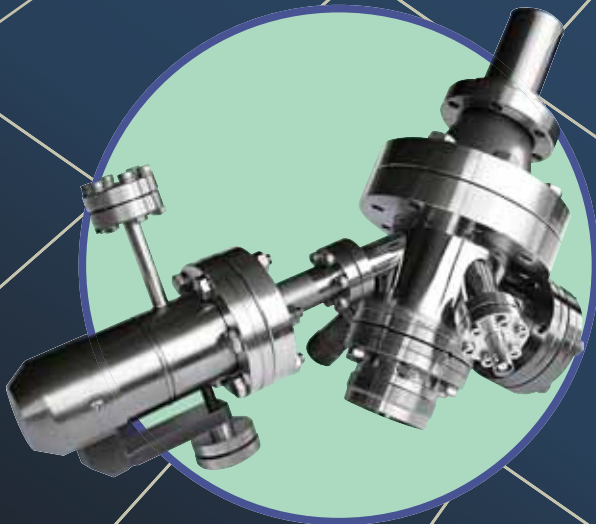


Sputter Ion Gun

IB-103

- **Lightweight and Stable Controller Electronics**
- **Low Cost, High Performance**
- **X,Y Positioning and Focusing**
- **Easy Gas Introduction via Variable Leak Valve**



Sputter ion gun IB-103 with control electronics is designed for cleaning the sample or the probe by ion sputtering in UHV.



Accessories

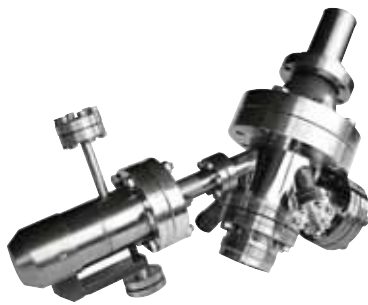
Sputter Ion Gun IB-103

Component

Sputter Ion Gun	: 1
Controller Electronics	: 1
Cable	: 1
Manual	: 1

Specifications

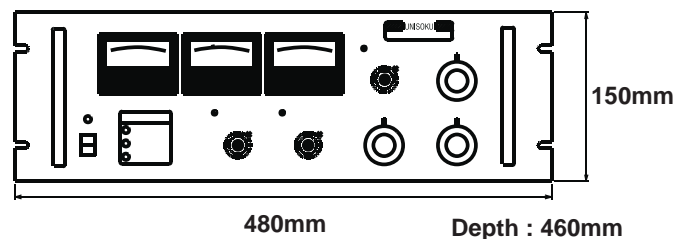
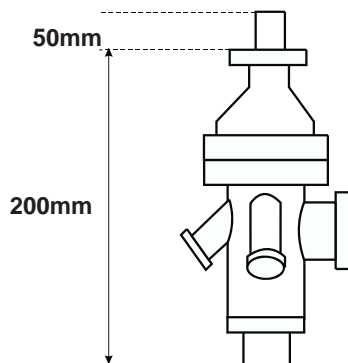
Accelerating Voltage	: 3 kV max
Emission Current	: 0 - 30 mA
Beam Size	: less than phi 10 mm
Raster Area	: 6 mm X 6 mm
Operating Pressure	: less than 5×10^{-5} Torr
Bakeout Temperature	: less than 200 celsius degree
Mounting Flange	: phi 70 ICF
Variable Leak Valve	: Input Connection Flange phi 34 ICF
Working Distance	: 100 - 150 mm
Power Source	: AC 100 V (50/60 Hz)
Weight	: Sputter Ion Gun 6 kg : Controller Electronics 12 kg



Sputter Ion Gun



Controller Electronics



Instrumental components subject to change without prior notice for improvement in performance.

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